

Substitute for form 1449A/PTO		<i>Complete if Known</i>	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>		Application Number	10/757,030
		Filing Date	January 13, 2004
		First Named Inventor	Xie, Jun
		Art Unit	3754-3287
		Examiner Name	Unassigned <i>Instrument</i>
Sheet <i>E</i> 1	of 1	Attorney Docket Number 020859-002610US	

JUN 18 2004

Examiner Signature		Date Considered	
--------------------	---	-----------------	---

¹EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ²Applicant's unique citation designation number (optional). ³Kind Codes of U.S. Patent Documents at www.uspto.gov or MPEP 801.04. ⁴Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁵For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁶Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁷Applicant is to place a check mark here if English language Translation is attached.



MAY 24 2004

PTO/SB/08B (08-03)

Substitute for form 1449B/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet

1

of

1

Complete If Known

Application Number	10/757,030
Filing Date	January 13, 2004
First Named Inventor	Xie, Jun
Art Unit	3754 TJB
Examiner Name	Unassigned <i>Bastromelli</i>
Attorney Docket Number	020859-002610US

NON PATENT LITERATURE DOCUMENTS		
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
<i>JJ</i>	1	DUBOIS et al., Electrostatically Actuated Gas Microvalve Based on a Ta-Si-N Membrane, 14th IEEE International Conference on Micro Electro Mechanical Systems, 2001, pp. 535-538.
<i>JJ</i>	2	KOVACS, G.T.A., Micro Machined Transducers Sourcebook, McGraw-Hill, 1998, pp. 819-838, and 883-899.
<i>JJ</i>	3	WIJNGAART et al., A High-Storke, High-Pressure Electrostatic Actuator for Valve Applications, Sensors and Actuators, A 100 (2002), pp 264-271.
<i>JJ</i>	4	WU et al., MEMS Flow Sensors for Nano-Fluidic Applications, Sensors and Actuators A: Physical, 89 (1-2) (2001) pp 152-158.
<i>JJ</i>	5	YAO et al., Dielectric Charging Effects on Parylene Electrostatic Actuators, IEEE, 2002, pp 614-617.
<i>JJ</i>	6	YANG et al., Surface Micromachined Leakage Proof Parylene Check Valve, the 14th IEEE International Conference on Micro Electro Mechanical Systems (MEMS'01), Interlaken, Switzerland, 2001, pp 539-542.

Examiner Signature	<i>[Signature]</i>	Date Considered	<i>7/22/03</i>
--------------------	--------------------	-----------------	----------------

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Applicant's unique citation designation number (optional). ²Applicant is to place a check mark here if English language Translation is attached.

BEST AVAILABLE COPY